ARTICLE IN PRESS

Scripta MATERIALIA

Scripta Materialia xxx (2015) xxx-xxx

Contents lists available at ScienceDirect

Scripta Materialia

journal homepage: www.elsevier.com/locate/scriptamat

Evaluation of Atomic Layer Deposition coating as gas barrier against hydrogen gas and humidity

Damoon Sohrabi Baba Heidary *, Clive A. Randall

Center for Dielectrics and Piezoelectrics, Materials Research Institute, The Pennsylvania State University, University Park, PA 16802, USA

ARTICLE INFO

13Article history:13Received 29 April 201514Received 29 April 201515Accepted 10 May 201516Available online xxxx

- Keywords:
 Atomic Layer Deposition
 Gas barrier
- 20 Hydrogen degradation
- 21 Varistor
- 22 Diffusion 23

34 35 Varistors or variable resistors are passive components, 36 which are used in protection against voltage surges, that shunt the excess charge to the ground [1-4]. The design is typically 37 around ceramic materials based on ZnO with dopants and sintering 38 aids added to control the nature of the controlled breakdown pro-39 40 cess and minimize the leakage in the stand-by operational condi-41 tion [4,5]. The grain size and the grain boundary compositions are critical and are back-to-back Schottky barriers controlling 42 these conditions [6.7.1.3]. There is concern about the packaging 43 of varistor components at the atmosphere in which they are 44 45 exposed to humidity or hydrogen gas [8]. The source of hydrogen gas could, for example, be the out-gassing of corrosive atmo-46 spheres from incompletely cured epoxies and or electrolytic capac-47 48 itor seal failure [9–11].

There have been earlier studies on the atmosphere sensitivity to 49 varistors, such as the work of Sonder et al. [12] who have studied 50 51 systematically the effects of reducing atmosphere on the resistivity 52 degradation of ZnO varistors. In their case, a reductive agent of CO 53 and different percentage of oxygen and inert gas at the interval temperature of 150-800 °C were considered. It was found that 54 55 ZnO varistors can be degraded by annealing at 260 °C in a CO/CO₂ atmosphere, and showing resistance can decrease from 56 10^{10} to $10^4\,\Omega$ after 33 h of exposure to CO/CO_2. In addition, there 57 are additional reports of resistivity degradation of ZnO varistors 58 due to hydrogen gas exposure [11,13]. It will be shown in this 59

E-mail address: dus255@psu.edu (D. Sohrabi Baba Heidary).

ABSTRACT

Effectiveness of HfO_2 Atomic Layer Deposition coatings has been studied on ZnO varistors by *I*–V tests, impedance spectroscopy, and highly accelerated life test. Based on impedance spectroscopy analyses, the proton diffusion coefficient was measured to be 400 K times less in the coating. Transmission electron microscopy analysis shows that Atomic Layer Deposition films are continuous and conformal. After exposure to high temperature, partial crystallization was detected in the coating and increases proton diffusion coefficient by 150 times.

© 2015 Acta Materialia Inc. Published by Elsevier Ltd. All rights reserved.

33

60

61

62

63

64

65

66

67

68

69

70

71

72

73

74

75

76 77

78

79

80

81

82

83

84

85

86

87

88

25

26

27

28

report that the leakage current can increase from 10^{-8} to 10^{-4} A at 170 °C after one hour exposure to hydrogen gas.

ALD (Atomic Layer Deposition) coatings demonstrate a good gas barrier property [14–17] on various substrates, which makes them promising to hinder the degradation process. In this letter, the effect of exposure of ZnO varistors to forming gas (4% hydrogen and 96% nitrogen) and humidity has been studied, and the application of ALD coating as a gas barrier layer has been evaluated. In addition, the proton diffusion coefficient has been measured for both ZnO varistor and HfO₂ ALD layers to demonstrate effectiveness as gas and humidity barriers for ZnO based varistors.

A commercial ZnO varistor was cut to $15 \times 15 \times 1.4$ mm and ground up to 1200 grit sandpaper, then a circular Pt electrode with area of 5 mm² was sputtered to the center of both sides of samples. Impedance spectroscopy was applied, by SR-830-DSP Lock-in connected to a charge measurement system (the test was conducted in Material Characterization Lab of the Pennsylvania State University), to trace the degradation in grain and grain boundaries at 135, 155, and 175 °C, when they were exposed to forming gas (4% hydrogen and 96% nitrogen) for 3 h.

 HfO_2 ALD coating was applied around the devices using 150LE, The Kurt J. Lesker Co. and the precursor of TDMAH, tetrakis (dimethylamino) hafnium (IV) ($C_8H_{24}N_4Hf$), and water. Dose times of the precursor and water were 0.15 and 0.03 s, followed by the purge time of 10 s at the temperature of 200 °C and the pressure of 400 mtorr. The growth rate was measured 1.3 Å/cycle.

Another set of tests was leakage current measurement to monitor the amount of resistivity degradation. The varistors with different coating thicknesses were exposed to forming gas in the

1359-6462/© 2015 Acta Materialia Inc. Published by Elsevier Ltd. All rights reserved.



5 6

10

^{*} Corresponding author. Tel.: +1 (917) 376 7737.

http://dx.doi.org/10.1016/j.scriptamat.2015.05.013

122

123

124

125

126

127

128

129

130

131 132

135

136

137

138

139

140

141

142

143

2

D. Sohrabi Baba Heidary, C.A. Randall/Scripta Materialia xxx (2015) xxx-xxx

89 interval temperature of 80-290 °C; for every 20 °C increment, they 90 were held for 30 min, while the leakage current was measured 91 every second under an applied voltage of 5 V. A Highly 92 Accelerated Life Test (HALT) was executed by Temperature 93 Humidity Chamber (Blue M, Illinois, USA) at the temperature of 90 °C and humidity of 85% for 120 h, under 100 V applied voltage 94 95 on the coated and uncoated samples. TEM samples were obtained by FEI Helios NanoLab 660 FIB/FESEM. The TEM analysis was exe-96 97 cuted by JEOL 2010F.

Impedance spectroscopy analysis is an effective method to 98 monitor the relative changes in resistivity and capacitance in grain 99 100 and grain boundary microstructures. We represent the impedance data (Z', Z") in the complex plane in the form of Nyquist or Cole-101 Cole plots, noting the changes with the experimental variable of 102 103 different exposure times in Figure 1(a). It was found that Cole-104 Cole plots can be fitted well with the two impedance element 105 equivalent circuits shown in Figure 1(b), the electrode contribution 106 is negligible in the ZnO varistor, and the largest contribution comes 107 from grain boundary barriers. Our approach is consistent and builds on the analysis of Andres-Verges and West [18], where 108 109 the grain impedance can be approximated with a pair of ideal 110 capacitor and resistor. The capacitor is representative of the transient charge storage in grains and the resistor the bulk resistivity 111 of ZnO crystals. For the grain boundary circuit representation, 112 113 another element, CPE (constant phase element [19]), is added to 114 consider the inhomogeneity over all the grain boundaries [20].

The resistance of grains and grain boundaries under different hydrogen gas exposure times is shown in Figure 1(c). The resistance of the grain boundaries at the beginning of the exposure is 100 times higher than the resistance of grains at the end of exposure. While the GB resistance decreases an order of magnitude, the grain resistance is essentially invariant under the gas exposure conditions used here. The change in GB resistance can be related to proton concentration acting as a donor dopant reducing the interfacial grain boundary resistance [11].

The change in GB resistance can be used to determine the diffusion of hydrogen into the grain boundaries, by defining appropriate boundary conditions and solving Fick's law, one can estimate diffusion coefficient of protons at 135 °C in grain boundaries [21]. One of the boundary conditions can be concluded from the fact that the entering rate of total hydrogen ions $\left(\frac{dN(t)}{dt}\right)$ to the device is proportional to the concentration difference between the atmosphere (C_0) and the surface (C_s) , which can be represented as:

$$\frac{dN(t)}{dt} = \alpha(C_0 - C_S) \tag{1}$$

where α is a proportionality constant.

The other boundary conditions are obtained based on the assumption that the diffusion system is semi-infinite. Here, we need to consider an additional assumption, which is that the Pt electrode is not a barrier against proton diffusion. Regarding the hydrogen diffusion coefficient in Pt [22,23] and ZnO [11,24–26], the diffusion coefficient in Pt is several orders of magnitude higher than the diffusion coefficient in ZnO in the temperature interval of the present work. So the above mentioned assumption is valid.

The same impedance spectroscopy tests were executed at 155 144 and 175 °C, and the calculated diffusion coefficients are shown in 145 Figure 1(d). One can find the best line that passes those three 146 points, and find the activation enthalpy for proton diffusion, as 147 0.88 eV, which is fairly close to the reported values of 1.21 [25] 148 and 0.91 eV [11] for proton diffusion in ZnO. However, it is 149 reported as 0.17 eV [24] elsewhere. Nickel [26] has thoroughly 150 studied the proton diffusion coefficient in single and polycrystal 151 ZnO thin films. He argued that the activation enthalpy can depend 152 on temperature and reported 0.75 eV for ZnO poly crystals at 153 155 °C. It should be noted that the resultant diffusion coefficients 154



Figure 1. (a) Cole–Cole plots of the ZnO varistor exposed to forming gas at 135 °C at different exposure times; (b) equivalent circuit; (c) resistance of grains and grain boundaries vs. gas exposure time at 135 °C; (d) proton diffusion coefficients vs. reciprocal temperature in grain boundaries of ZnO varistors, virgin HfO₂ ALD layers and crystalized HfO₂ ALD layers.

Please cite this article in press as: D. Sohrabi Baba Heidary, C.A. Randall, Scripta Mater. (2015), http://dx.doi.org/10.1016/j.scriptamat.2015.05.013

Download English Version:

https://daneshyari.com/en/article/7912818

Download Persian Version:

https://daneshyari.com/article/7912818

Daneshyari.com